

LIST OF PUBLICATIONS CITED BY APPLICANT	Attorney Docket No. HAG 111	Serial No. Not Assigned
	Applicant Tsutomu SHOKI	
	Filing Date Herewith	Group

U.S. PTO  
09/052070  
03/31/96

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
AR		5,005,075	04/02/91	Kobayashi et al	378	35	01/30/90
AR		5,178,977	01/12/93	Yamada et al	378	35	01/18/90

FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
AR	JP	7-75219	08/09/95	Fujitsu Ltd.			07/25/89

OTHER PUBLICATIONS (Including Author, Title, Date, Pertinent Pages)	
AR	1) English language abstract: Japanese Laid-Open Patent No. 7-75219. 8/95
AR	2) Yamaguchi, Y.I. et al, "Properties of SiC Film as X-Ray Mask Membrane," Materials Research Laboratory, Hoya Corporation, pp. 197-210. 1993
EXAMINER J. Dorasco	DATE CONSIDERED 3/99
*EXAMINER:	Initial if reference considered, whether or not citation is in conformance and not considered. Include a copy of this form with the next communication to applicant.